

Amendments to the Specification

Please replace the paragraph beginning at page 14, line 2, with the following rewritten paragraph:

~~The present invention relates to different types~~ Embodiments of micromirror spectrometers using MEMS (Micro Electro Mechanical Systems) ~~for various applications in the UV, VIS, NIR and MIR wavelength regions~~ technology are disclosed. ~~The invention enables a~~ Some embodiments enable wavelength selection using a micro scanning mirror and integrated grating. ~~on a much smaller scale than previously encountered conventional diffraction grating monochromators. Especially small designs are obtained via simultaneous usage of collimation optics for both spatial filters, by using~~ Also, the entrance and exit slit apertures, ~~which are~~ can be located very close together. ~~Until now, the spatial filters themselves are not part of the miniaturization. The utilization of the precision from this of MEMS technology allows for the reproducible fabrication of slits with defined geometries and surface roughness and for accurate spatial classification towards positioning of the slits relative to the rotation rotational axis of the diffraction grating. Therefore the assembly and adjustment effort of the monochromator is reduced. Due to the option of~~ By including additional slit apertures, several independent monochromator channels with crossed beam paths can be created; ~~whereas all remaining optical elements (diffraction grating and collimator optic) are utilized together. Such additional channels can serve, for example, as reference measurements of channels for measuring a radiation source, or enable as monitoring channels enabling the direct optical control of the grating torsion angle, as a monitoring channel. The goal of the invention is to define a simple design and arrangement for monochromators based upon micromechanical elements, which avoids all disadvantages described above.~~